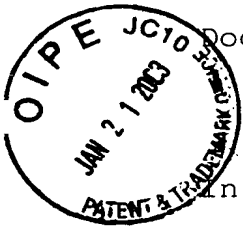


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Socket No. 216-028B

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: KATSIR, D. ET AL.  
Serial No. : 09/893,914  
Filed : June 28, 2001  
For : METHOD FOR PRODUCING HIGH SURFACE  
: AREA FOIL ELECTRODES  
Art Unit : 1775  
Examiner : Stein, Stephen J.

New York, New York 10036  
January 17, 2003

Commissioner for Patents  
Washington D.C. 20231

AMENDMENT

This Amendment is being filed in response to the  
Office Action that was mailed September 17, 2002. Kindly amend  
the subject application as follows:

IN THE CLAIMS

Kindly amend ~~claims 29 and 34~~ as follows:

Kindly amend 29 and 34 to read as follows:

BL  
29. (Twice Amended) An article of manufacture having a vacuum  
deposited fractal surficial structure, which fractal surficial  
structure includes both valve metal and an oxide thereof, the  
valve metal being selected from the group consisting of  
aluminum, titanium, tantalum, niobium, zirconium, silicon,  
thorium, cadmium and tungsten.